

Day : Friday
Date: 10/31/2003

**PALM INTRANET**

Time: 09:25:59

Inventor Name Search Result

Your Search was:

Last Name = MABOUDIAN

First Name = ROYA

Application#	Patent#	Status	Date Filed	Title	Inventor Name 2
10086652	Not Issued	030	02/28/2002	VAPOR DEPOSITION OF DIHALODIALKLYSILANES	MABOUDIAN, ROYA
08866833	6114044	150	05/30/1997	METHOD OF DRYING PASSIVATED MICROMACHINES BY DEWETTING FROM A LIQUID-BASED PROCESS	MABOUDIAN , ROYA

Inventor Search Completed: No Records to Display.

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Day : Friday
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Time: 09:26:17



Inventor Name Search Result

Your Search was:

Last Name = CARRARO

First Name = CARLO

Application#	Patent#	Status	Date Filed	Title	Inventor Name 1
10086652	Not Issued	030	02/28/2002	VAPOR DEPOSITION OF DIHALODIALKLYSILANES	CARRARO, CARLO

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Day : Friday
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PALM INTRANET

Inventor Name Search Result

Your Search was:

Last Name = FREY

First Name = WILHELM

Application#	Patent#	Status	Date Filed	Title	Inventor Name 32
60449745	Not Issued	020	02/24/2003	INTEGRATED MONOLITHIC TRI-AXIAL MICROMACHINED ACCELEROMETER	FREY, WILHELM
10613459	Not Issued	019	01/01/0001	METHOD FOR PRODUCING INTEGRATED MICROSYSTEMS	FREY, WILHELM
10374197	Not Issued	020	02/26/2003	METHOD OF FABRICATING MICROSTRUCTURES AND DEVICES MADE THEREFROM	FREY, WILHELM
10371809	Not Issued	020	02/21/2003	DEVICE AND METHOD FOR ELECTROSTATICALLY LEVITATING A DISK AND METHOD FOR USING AN ELECTROSTATIC LEVITATED DISK AS A SENSOR	FREY, WILHELM
10343820	Not Issued	020	07/02/2003	MODULE, ESPECIALLY A WAFER MODULE	FREY, WILHELM
10327532	Not Issued	020	12/20/2002	APPARATUS, METHOD AND SYSTEM FOR PROVIDING ENHANCED MECHANICAL PROTECTION FOR THIN BEAMS	FREY, WILHELM
10327273	Not Issued	019	12/20/2002	DIFFERENTIAL IN-PLANE TUNNELING CURRENT SENSOR	FREY, WILHELM
10324911	Not Issued	020	12/20/2002	ARRANGEMENT, METHOD, AND SYSTEM TO REDUCE THE PLAY OF MICRO-MECHANICAL PRODUCED GEARS	FREY, WILHELM
10193351	Not Issued	041	07/10/2002	METHOD FOR MANUFACTURING A SEMICONDUCTOR DEVICE	FREY, WILHELM
10086652	Not Issued	030	02/28/2002	VAPOR DEPOSITION OF DIHALODIALKLYLSILANES	FREY, WILHELM
10077422	Not Issued	041	02/14/2002	MICROMECHANICAL PART AND METHOD FOR ITS MANUFACTURE	FREY, WILHELM

<u>10070054</u>	Not Issued	093	07/17/2002	MICROMECHANICAL OSCILLATING DEVICE	FREY, WILHELM
<u>10057455</u>	Not Issued	030	01/24/2002	METHOD OF MANUFACTURING A MICROMECHANICAL COMPONENT	FREY, WILHELM
<u>10016259</u>	6645800	150	10/26/2001	A METHOD FOR PRODUCING OF A FIELD-EFFECT STRUCTURE	FREY, WILHELM
<u>09937926</u>	Not Issued	094	12/26/2001	ELECTROCHEMICAL ETCHING CELL	FREY, WILHELM
<u>09805830</u>	6489864	150	03/14/2001	FILTER FOR ELECTRIC SIGNALS	FREY, WILHELM
<u>09656546</u>	6592664	150	09/06/2000	METHOD AND DEVICE FOR EPITAXIAL DEPOSITION OF ATOMS OR MOLECULES FROM A REACTIVE GAS ON A DEPOSITION SURFACE OF A SUBSTRATE	FREY, WILHELM
<u>09623670</u>	6486665	150	11/21/2000	MAGNETIC FIELD SENSOR HAVING DEFORMABLE CONDUCTOR LOOP SEGMENT	FREY, WILHELM
<u>09613131</u>	Not Issued	095	07/10/2000	SENSOR, IN PARTICULAR THERMAL SENSOR, AND METHOD FOR MANUFACTURING A LARGELY SELF-SUPPORTING MEMBRANE	FREY, WILHELM
<u>09550789</u>	6648389	150	04/17/2000	PROCESS FOR MANIPULATING COMPONENTS, A MICROTOOL FOR IMPLEMENTING THE PROCESS, AND A PROCESS FOR MANUFACTURING THE MICROTOOL OR MICROTOOL PARTS	FREY, WILHELM
<u>09507583</u>	6443008	150	02/19/2000	DECOUPLED MULTI-DISK GYROSCOPE	FREY, WILHELM
<u>09438072</u>	6555443	150	11/10/1999	METHOD FOR PRODUCTION OF A THIN FILM AND A THIN-FILM SOLAR CELL, IN PARTICULAR, ON A CARRIER SUBSTRATE	FREY, WILHELM
<u>09423532</u>	6360604	150	10/09/1999	ACCELERATION SENSOR	FREY, WILHELM
<u>09406272</u>	6372656	150	09/24/1999	METHOD OF PRODUCING A RADIATION SENSOR	FREY, WILHELM
<u>09367760</u>	6369931	150	08/18/1999	METHOD FOR MANUFACTURING A MICROMECHANICAL DEVICE	FREY, WILHELM
<u>09355373</u>	Not Issued	120	10/25/1999	THERMAL MEMBRANE SENSOR AND METHOD FOR	FREY, WILHELM

				THE PRODUCTION THEREOF	
<u>09238959</u>	Not Issued	093	01/27/1999	METHOD FOR MANUFACTURING BREAKAWAY LAYERS FOR DETACHING DEPOSITED LAYE	FREY , WILHELM
<u>09235018</u>	<u>6217647</u>	150	01/21/1999	METHOD FOR PRODUCING A MONOCRYSTALLINE LAYER OF A CONDUCTING OR SEMICONDUCTING MATERIAL	FREY, WILHELM
<u>09209941</u>	<u>6174746</u>	150	12/11/1998	METHOD OF PRODUCING OPTICAL WAVEGUIDES	FREY , WILHELM
<u>09080829</u>	Not Issued	161	05/18/1998	PRESSURE SENSOR	FREY , WILHELM
<u>09064495</u>	<u>5996409</u>	150	04/22/1998	ACCELERATION SENSING DEVICE	FREY , WILHELM
<u>09061704</u>	Not Issued	161	04/16/1998	ACCELERATION SWITCH	FREY , WILHELM

Inventor Search Completed: No Records to Display.

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	<input type="text" value="FREY"/>	<input type="text" value="WILHELM"/>	

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Day : Friday
Date: 10/31/2003

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**PALM INTRANET****Inventor Name Search Result**

Your Search was:

Last Name = ASHURST

First Name = WILLIAM

Application#	Patent#	Status	Date Filed	Title	Inventor Name 1
10086652	Not Issued	030	02/28/2002	VAPOR DEPOSITION OF DIHALODIALKLYSILANES	ASHURST, WILLIAM R.

Inventor Search Completed: No Records to Display.

Search Another: Inventor

Last Name	First Name	
<input type="text" value="ASHURST"/>	<input type="text" value="WILLIAM"/>	<input type="button" value="Search"/>

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L Number	Hits	Search Text	DB	Time stamp
3	17	((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS) with stiction).clm.	USPAT; US-PGPUB	2003/10/31 10:17
4	285	((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS)) and (Ashurst.in. or Maboudian.in. or Carraro.in. or Frey.in. or (Regents near3 University near2 California).as.)	USPAT; US-PGPUB	2003/10/31 09:58
6	10	((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS)) and (Ashurst.in. or Maboudian.in. or Carraro.in. or Frey.in. or (Regents near3 University near2 California).as.)) and (\$15silyloxy or OTS or FDTS or FOTS or DDMS or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane)	USPAT; US-PGPUB	2003/10/31 10:03
7	2	((S20silyloxy or OTS or FDTS or FOTS or DDMS or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane) with (vapor\$3)) and (Ashurst.in. or Maboudian.in. or Carraro.in. or Frey.in. or (Regents near3 University near2 California).as.)	USPAT; US-PGPUB	2003/10/31 09:58
8	19	((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS)) and (Ashurst.in. or Maboudian.in. or Carraro.in. or Frey.in. or (Regents near3 University near2 California).as.)	EPO; JPO; DERWENT; IBM_TDB	2003/10/31 10:50
9	0	((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS)) and (Ashurst.in. or Maboudian.in. or Carraro.in. or Frey.in. or (Regents near3 University near2 California).as.)) and (\$15silyloxy or OTS or FDTS or FOTS or DDMS or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane)	EPO; JPO; DERWENT; IBM_TDB	2003/10/31 10:24

10	0	(((\$20silyloxy or OTS or FDTS or FOTS or DDMS or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane) same (vapor\$3)) and (Ashurst or Maboudian or Carraro or Frey or (Regents near3 University near2 California))	EPO; JPO; DERWENT; IBM_TDB	2003/10/31 09:56
11	1123	(427/58).CCLS.	USPAT;	2003/10/31 09:56
12	2267	(427/248.1,255.14,255.6,255.23).CCLS.	US-PGPUB	2003/10/31 09:56
13	2051	(427/421).CCLS.	USPAT;	2003/10/31 09:57
14	361	(427/255.18,255.27).CCLS.	US-PGPUB	2003/10/31 09:57
16	5671	((427/58).CCLS.) ((427/248.1,255.14,255.6,255.23).CCLS.) ((427/421).CCLS.) ((427/255.18,255.27).CCLS.) ((427/255.17).CCLS.)	USPAT; US-PGPUB	2003/10/31 09:57
17	0	((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS)) and ((427/255.17).CCLS.)	USPAT; US-PGPUB	2003/10/31 10:50
18	1	(((\$20silyloxy or OTS or FDTS or FOTS or DDMS or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane)) and ((427/255.17).CCLS.)	USPAT; US-PGPUB	2003/10/31 09:59
15	67	(427/255.17).CCLS.	USPAT;	2003/10/31 09:59
19	1	((427/58).CCLS.) ((427/248.1,255.6,255.23).CCLS.) ((427/421).CCLS.) ((427/255.18,255.27).CCLS.) ((427/255.17).CCLS.) and ((\$15silyloxy or OTS or FDTS or FOTS or DDMS or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane) with (vapor\$3) with (coat\$3 or film or layer or SAM or monolayer or apply\$3 or application or deposit\$3))	US-PGPUB USPAT; US-PGPUB	2003/10/31 10:05

20	4	((427/58).CCLS.) ((427/248.1,255.14,255.6,255.23).CCLS.) ((427/421).CCLS.) ((427/255.18,255.27).CCLS.) ((427/255.17).CCLS.)) and ((\$15silyloxy or OTS or FOTS or FOTS or DDMS or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane) with (SAM or monolayer))	USPAT; US-PGPUB	2003/10/31 10:05
21	25	((15silyloxy or OTS or FOTS or FOTS or DDMS or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane) with (vapor\$3) with (coat\$3 or film or layer or SAM or monolayer or apply\$3 or application or deposit\$3))	USPAT; US-PGPUB	2003/10/31 11:12
22	29	((15silyloxy or OTS or FOTS or FOTS or DDMS or DMDS or DMDCS or DCDMS or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane) with (vapor\$3) with (coat\$3 or film or layer or SAM or monolayer or apply\$3 or application or deposit\$3))	USPAT; US-PGPUB	2003/10/31 10:11
23	41	((15silyloxy or OTS or FOTS or FOTS or DDMS or DMDS or DMDCS or DCDMS or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane) with (vapor\$8 or \$4CVD) with (coat\$3 or film or layer or SAM or monolayer or apply\$3 or application or deposit\$3))	USPAT; US-PGPUB	2003/10/31 11:13

24	16	(((\$15silyloxy or OTS or FDTS or FOTS or DDMS or DMDS or DMDCS or DCDMS or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane) with (vapor\$8 or \$4CVD) with (coat\$3 or film or layer or SAM or monolayer or apply\$3 or application or deposit\$3))) not ((((\$15silyloxy or OTS or FDTS or FOTS or DDMS or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane) with (vapor\$3) with (coat\$3 or film or layer or SAM or monolayer or apply\$3 or application or deposit\$3)))	USPAT; US-PGPUB	2003/10/31 10:16
25	2	6576489.pn. or 5331454.pn.	USPAT; US-PGPUB	2003/10/31 10:16
26	93	((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS)) and ((\$4CVD or vapor\$4 or gas\$4) with (monolayer or (mono adj layer) or SAM))	USPAT; US-PGPUB	2003/10/31 10:24
27	14	((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS)) and ((\$4CVD or vapor\$4 or gas\$4) with (monolayer or (mono adj layer) or SAM))) and (((427/58).CCLS.) ((427/248.1,255.14,255.6,255.23).CCLS.) ((427/421).CCLS.) ((427/255.18,255.27).CCLS.) ((427/255.17).CCLS.)))	USPAT; US-PGPUB	2003/10/31 10:19
28	79	((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS)) and ((\$4CVD or vapor\$4 or gas\$4) with (monolayer or (mono adj layer) or SAM))) not (((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS)) and ((\$4CVD or vapor\$4 or gas\$4) with (monolayer or (mono adj layer) or SAM))) and (((427/58).CCLS.) ((427/248.1,255.14,255.6,255.23).CCLS.) ((427/421).CCLS.) ((427/255.18,255.27).CCLS.) ((427/255.17).CCLS.)))	USPAT; US-PGPUB	2003/10/31 10:24

29	0	(((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS))) and ((\$4CVD or vapor\$4 or gas\$4) with (monolayer or (mono adj layer) or SAM))) not (((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS))) and ((\$4CVD or vapor\$4 or gas\$4) with (monolayer or (mono adj layer) or SAM))) and (((427/58).CCLS.) ((427/248.1,255.14,255.6,255.23).CCLS.) ((427/421).CCLS.) ((427/255.18,255.27).CCLS.) ((427/255.17).CCLS.)))) and ((\$15silyloxy or OTS or FDTs or FOTS or DDMS or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or \$12silane) same (coat\$3 or film or layer or apply\$3 or vapor\$4 or application or \$4CVD or monolayer or SAM or (mono adj layer)))	EPO; JPO; DERWENT; IBM_TDB	2003/10/31 10:26
30	11	(((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS))) and ((\$4CVD or vapor\$4 or gas\$4) with (monolayer or (mono adj layer) or SAM))) not (((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS))) and ((\$4CVD or vapor\$4 or gas\$4) with (monolayer or (mono adj layer) or SAM))) and (((427/58).CCLS.) ((427/248.1,255.14,255.6,255.23).CCLS.) ((427/421).CCLS.) ((427/255.18,255.27).CCLS.) ((427/255.17).CCLS.)))) and ((\$15silyloxy or OTS or FDTs or FOTS or DDMS or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or \$12silane) same (coat\$3 or film or layer or apply\$3 or vapor\$4 or application or \$4CVD or monolayer or SAM or (mono adj layer)))	USPAT; US-PGPUB	2003/10/31 10:32

31	82	(((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane) same (coat\$3 or film or layer or apply\$3 or application or monolayer or SAM or (mono adj layer)) same (vapor\$8 or \$4CVD))	USPAT; US-PGPUB	2003/10/31 10:34
32	119	(((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS or DDMS or DMDS) same (coat\$3 or film or layer or apply\$3 or application or monolayer or SAM or (mono adj layer)) same (vapor\$8 or \$4CVD))	USPAT; US-PGPUB	2003/10/31 11:09
33	11957	(((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS or DDMS))	USPAT; US-PGPUB	2003/10/31 11:14
34	341	((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS)) and ((((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS or DDMS)))	USPAT; US-PGPUB	2003/10/31 11:14
35	10856	(((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS)) and ((((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS or DDMS)))	USPAT; US-PGPUB	2003/10/31 10:51

36	10856	(((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS)) and ((((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS or DDMS)))	USPAT; US-PGPUB	2003/10/31 10:51
37	325	(((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS)) and ((((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS or DDMS)))) and ((((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS)) and ((((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS or DDMS))))	USPAT; US-PGPUB	2003/10/31 10:51
38	20	(((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS)) same ((((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS or DDMS))))	USPAT; US-PGPUB	2003/10/31 11:03

39	639	(((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS or DDMS) with (coat\$3 or deposit\$3 or \$4CVD or apply\$3 or application or SAM or monolayer or (mono adj layer) or vapor\$4 or gas\$4)))	USPAT; US-PGPUB	2003/10/31 11:01
40	17	((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS)) and ((((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS or DDMS) with (coat\$3 or deposit\$3 or \$4CVD or apply\$3 or application or SAM or monolayer or (mono adj layer) or vapor\$4 or gas\$4))))	USPAT; US-PGPUB	2003/10/31 10:56
41	13	((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS)) and ((((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS or DDMS) with (coat\$3 or deposit\$3 or \$4CVD or apply\$3 or application or SAM or monolayer or (mono adj layer) or vapor\$4 or gas\$4)))) not (((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS)) same ((((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS or DDMS))))	USPAT; US-PGPUB	2003/10/31 10:57

42	46	(((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS or DDMS))) and (((427/58).CCLS.) ((427/248.1,255.14,255.6,255.23).CCLS.) ((427/421).CCLS.) ((427/255.18,255.27).CCLS.) ((427/255.17).CCLS.))	USPAT; US-PGPUB	2003/10/31 10:57
43	16	(\$15silyloxy same (dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS or DDMS))	USPAT; US-PGPUB	2003/10/31 11:15
44	11	((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS)) same (\$12silane) same (monolayer or SAM or (Mono adj layer))	USPAT; US-PGPUB	2003/10/31 11:15
45	27	\$12silane with (SAM or monolayer or (mono adj layer)) with (\$4CVD or gas\$4 or vapor\$3)	USPAT; US-PGPUB	2003/10/31 11:16
46	24	(((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS or DDMS or DMDS) same (coat\$3 or film or layer or apply\$3 or application or monolayer or SAM or (mono adj layer)) same (vapor\$8 or \$4CVD or gas\$4))	EPO; JPO; DERWENT; IBM_TDB	2003/10/31 11:10
47	13	(((\$15silyloxy or OTS or FDTS or FOTS or DDMS or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane) with (vapor\$3) with (coat\$3 or film or layer or SAM or monolayer or apply\$3 or application or deposit\$3))	EPO; JPO; DERWENT; IBM_TDB	2003/10/31 11:12

48	23	(((\$15silyloxy or OTS or FDTS or FOTS or DDMS or DMDS or DMDCS or DCDMS or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane) with (vapor\$8 or \$4CVD) with (coat\$3 or film or layer or SAM or monolayer or apply\$3 or application or deposit\$3))	EPO; JPO; DERWENT; IBM_TDB	2003/10/31 11:13
49	6	(((\$15silyloxy or OTS or FDTS or FOTS or DDMS or DMDS or DMDCS or DCDMS or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane) with (vapor\$8 or \$4CVD) with (coat\$3 or film or layer or SAM or monolayer or apply\$3 or application or deposit\$3))) not ((((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS or DDMS or DMDS) same (coat\$3 or film or layer or apply\$3 or application or monolayer or SAM or (mono adj layer)) same (vapor\$8 or \$4CVD or gas\$4))) or ((((\$15silyloxy or OTS or FDTS or FOTS or DDMS or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane) with (vapor\$3) with (coat\$3 or film or layer or SAM or monolayer or apply\$3 or application or deposit\$3))))	EPO; JPO; DERWENT; IBM_TDB	2003/10/31 11:13
50	2373	(((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS or DDMS))	EPO; JPO; DERWENT; IBM_TDB	2003/10/31 11:20

51	0	((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS)) and ((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS or DDMS)))	EPO; JPO; DERWENT; IBM_TDB	2003/10/31 11:19
52	0	(\$15silyloxy same (dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS or DDMS))	EPO; JPO; DERWENT; IBM_TDB	2003/10/31 11:15
53	1	((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS)) same (\$12silane) same (monolayer or SAM or (Mono adj layer))	EPO; JPO; DERWENT; IBM_TDB	2003/10/31 11:15
54	11	\$12silane same (SAM or monolayer or (mono adj layer)) same (\$4CVD or gas\$4 or vapor\$3)	EPO; JPO; DERWENT; IBM_TDB	2003/10/31 11:16
55	51	((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS)) and (SAM or monolayer or (mono adj layer))	EPO; JPO; DERWENT; IBM_TDB	2003/10/31 11:20
56	2	(((\$15silyloxy or dihalodialkylsilane or (dihalo adj dialkyl adj silane) or dialkyldihalosilane or (dialkyl adj dihalo adj silane) or dimethyldichlorosilane or dichlorodimethylsilane or diethyldichlorosilane or dichlorodiethylsilane or dipropyldichlorosilane or dichlorodipropylsilane or DCDMS or DMDCS or DDMS or \$14silane)) and ((MEMS or micromechanical or (micro adj mechanical) or (microelectromechanical) or (micro adj electro adj mechanical) or nanoelectromechanical or (nano adj electro adj mechanical) or NEMS or bioMEMS)) and (SAM or monolayer or (mono adj layer)))	EPO; JPO; DERWENT; IBM_TDB	2003/10/31 11:21
57	1	6190003.pn.	USPAT; US-PGPUB	2003/10/31 11:21